B.TECH. IN ELECTRONICS AND COMMUNICATION ENGINEERING (BTECVI)

Term-End Examination

December, 2013

BIELE-007: NANO - ELECTRONICS

Time: 3 hours Maximum Marks: 70

Nota: (i) Attenuat any segum questions

Note: (i) Attempt any seven questions.

- (ii) All questions carry equal marks.
- 1. (a) What are the methods available for oxide layer formation?
 - (b) How do we measure the oxide layer thickness in VLSI technology? 2x5=10
- 2. (a) Describe the following terms in detail-Velocity saturation.
 - (b) Hot electron effects. 2x5=10
- 3. What is Fin FET technology? How a Fin FET transistor design is inspired by the thin-body MOSFET technology?
- 4. What is silicon-on-nothing proces in nano technology? Explain the structure of double gate transistor using silicon-on-nothing process.
- 5. Explain the term quantum heterostructure, and discuss the example of quantum heterostructure confining the carrier in quasi-two dimension i.e. 'quantum wells'.

6.	Explain coulomb blockade effects and discuss the	10
	coulomb blockade in a tunnel junction with neat	
	sketch.	

- 7. Explain the structure of resonant tunneling transistor with its high frequency performance in detail.
- 8. Explain the chemical vapour deposition (CVD) technique to synthesize carbon nano tubes by catalytic growth process.
- 9. What are the importance of carbon nanotubes 10 based devices? Explain one of them in detail.
- **10**. (a) What is spin field-effect transistor (Spin FET)?
 - (b) Write a short note on Heterostructure based devices. 2x5=10